

U.S. Department of Commerce, Patent and Trademark Office				Atty Docket No.		Serial No.	
				PSI004-1C US		UNKNOWN	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Applicant(s)			
(Use several sheets if necessary)				Kwon, joonhyung;			
				Filing Date		Group	
				HEREWITH		unknown	
U.S. Patent Documents							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
Dr	AA	Re. 35,514	5/20/97	Albrecht et al	250	216	
Dr	AB	5,103,095	4/7/1/92	Elings et al	<del>250</del>	<del>306</del>	
Dr	AC	5,157,251	10/20/92	Albrecht et al	250	216	
Dr	AD	5,376,790	12/27/94	Linker et al	250	306	
Dr	AE	5,714,756	2/3/98	Park et al	250	306	
Dr	AF	5,854,487	12/29/98	Braunstein et al	250	306	
Dr	AG	5,877,891	3/2/99	Park et al	359	372	
Dr	AH	5,939,719	8/17/99	Park et al	250	306	
Dr	AI	6,057,546	5/2/00	Braunstein et al	250	306	
Dr	AJ	6,057,547	5/2/00	Park et al	250	307	
Dr	AK	6,185,991 B1	2/13/01	Hong et al	<del>73</del>	<del>405</del>	
Dr	AL	6,310,342 B1	10/30/01	Braunstein et al	250	306	
Foreign Patent Documents							
							Translation
		Document	Date	Country	Class	Subclass	Yes No
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
	AQ	Binnig G., et al, "Atomic Force Microscope", <i>Physical Review Letters</i> , Vol 56, No. 9, 3 March 1986 pages 930-933					
	AR	Hänsma, P.K., et al, "A new, optical lever based atomic force microscope", <i>J. Appl. Phys.</i> , 76(2) 15 July 1994, American Institute of Physics, pages 796-799					
	AS	Meyer, Gerhard et al, "Erratum: Novel optical approach to atomic force microscopy", <i>Appl. Phys. Lett.</i> 53(24), 12 December 1988, American Institute of Physics, pages 2400-2402					
	AT	"Dimension 3100 Scanning Probe Microscope The Most Versatile SPM Ever Manufactured", <a href="http://www.di.com/Products/Dim3100/D3100Main.html">www.di.com/Products/Dim3100/D3100Main.html</a> , Digital Instruments, Veeco Metrology Group ©1998-2001, print date 12/17/2001, 4 pages					
Examiner		Date Considered 70 Oct 25 2001					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.							

U.S. Department of Commerce, Patent and Trademark Office				Atty Docket No.		Serial No.	
				PSI004-1C US		UNKNOWN	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Applicant(s)			
(Use several sheets if necessary)				Kwon, joonhyung;			
				Filing Date		Group	
				HEREWITH		unknown	

U.S. Patent Documents							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AU						
	AV						

Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AW							
	AX							

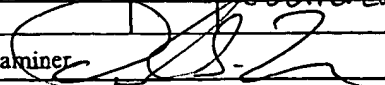
  

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)	
AY	"Dimension 3100 Scan Techniques Unparalleled Power and Versatility", <a href="http://www.di.com/Products/Dim/3000/D31-scantechniques.html">www.di.com/Products/Dim/3000/D31-scantechniques.html</a> , Digital Instruments Veeco Metrology Group, ©1998-2001, print date 12/17/2001, 2 pages
AZ	Babcock, K.L. et al, "Phase Imaging: Beyond Topography", Digital Instruments, 3 pages (believed to be prior to 2-15-02)
BA	"AutoProbe CP Research AP 2001", ThermoMicroscopes, 5 pages (believed to be prior to 2-15-02)
BB	"AutoProbe CP Research Scanning Probe Microscope", ThermoMicroscopes, 4 pages (believed to be prior to 2-15-02)
BC	"AutoProbe M5E AP-5001", ThermoMicroscopes, 4 pages (believed to be prior to 2-15-02)
BD	AutoProbe M5™ Scanning Probe Microscope, Microscopes Veeco Metrology Group, 2001© TM Microscopes, Veeco, 4 pages
BE	"TappingMode Imaging: Application and Technology", <a href="http://www.di.com/AppNotes/TapMode/TapModeMain.html">www.di.com/AppNotes/TapMode/TapModeMain.html</a> , Digital Instruments, Veeco Metrology Group, ©1995-2001, Digital Instruments, print date 12/17/2001, 5 pages
BF	"NanoScope Vertical Engage Scanner", <a href="http://www.di.com/Products/Multi/JVScanner.html">www.di.com/Products/Multi/JVScanner.html</a> , Digital Instruments Veeco Metrology Group, ©1996-2001, Digital Instruments, print date 12/17/2001, 1 page
BG	"NanoScope MultiMode Scanning Probe Microscope", <a href="http://www.di.com/products/Multi/MMAIone.html">www.di.com/products/Multi/MMAIone.html</a> , Digital Instruments Veeco Metrology Group, ©1996-2001, Digital Instruments, 8 page

Examiner <i>PS2</i>	Date Considered <i>2002/05/04</i>
---------------------	-----------------------------------

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

U.S. Department of Commerce, Patent and Trademark Office					Atty Docket No.		Serial No.	
					PSI 004-1C US		UNKNOWN	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					Applicant(s)			
(Use several sheets if necessary)					: Kwon, joonhyung:			
					Filing Date		Group	
					HERE WITH		UNKNOWN	
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	BH							
Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	BI							
	BJ							
	BK							
	BL							
	BM							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
	BN	<u>"NanoScope® MultiMode™ SPM The World's Highest Resolution SPM",</u> <u>www.di.com/Products/Multi/MMMain.html, Digital Instruments Veeco Metrology Group, ©1995-2001,</u> <u>Digital Instruments, print date 12/17/2001 7 pages</u>						
	BO	<u>"Products", Digital Instruments, Veeco Metrology Group Products,</u> <u>www.di.com/products2/products_all.html, print date 12/17/01, 5 pages</u>						
	BP	<u>"AutoProbe CP Research The Most Flexible Research SPM", www.theermomicro.com/products/cp.htm,</u> <u>Microscopes Veeco Metrology Group, ©2001, print date 12/17/01, 2 pages</u>						
	BQ	<u>Manalis, S. R., et al, "High-speed atomic force microscopy using an integrated actuator and optical lever</u> <u>detection", Rev. Sci. Instrum. 67(9), September 1996, pages 3294-3297</u>						
	BR	<u>"The Dimension™ 5000 Scanning Probe Microscope", Digital Instruments, 8 pages</u> <u>(believed to be prior to 2-15-02)</u>						
	BS	<u>"The Dimension™ 3000 Scanning Probe Microscope", Digital Instruments, 6 pages</u> <u>(believed to be prior to 2-15-02)</u>						
	BT	<u>"The Enhanced Dimension™ 3100 Scanning Probe Microscope", Digital Instruments, 1 page</u> <u>(believed to be prior to 2-15-02)</u>						
	BU	<u>"Microlevers™ General Purpose Cantilevers", Park Scientific Instruments ©1998, 1 page</u> <u>(believed to be prior to 2-15-02)</u>						
Examiner								
		Date Considered 20 October 2004						
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								

U.S. Department of Commerce, Patent and Trademark Office	Application No.:	Unknown
	Filing Date:	Unknown
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	First Named Inventor:	Joonhyung Kwon
(Use several sheets if necessary)	Group Art Unit:	Unknown
	Examiner Name:	Unknown
	Confirmation No.:	Unknown
	Attorney Docket No.:	PSI004-IC US

## U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
<i>Dr</i>	1.	6,144,028 A	11-2000	Kley, Vic B.	<del>250</del>	<del>234</del>	
<i>Dr</i>	2.	5,705,814 A	01/1998	Young et al.	250	306	
<i>Dr</i>	3.	2002/0148955 A1	10/2002	Hill, Henry A.	<del>250</del>	<del>234</del>	
<i>Dr</i>	4.	5,939,709 A	08/1999	Ghislain et al.	<del>250</del>	<del>216</del>	
<i>Dr</i>	5.	5,672,816 A	09/1997	Park et al.	73	105	
<i>Dr</i>	6.	5,210,410 A	05/1993	Barrett, Robert	<del>250</del>	<del>234</del>	
<i>Dr</i>	7.	6,169,281 B1	01/2001	Chen et al.	<del>250</del>	<del>234</del>	
<i>Dr</i>	8.	5,948,972 A	09/1999	Samsavar et al.	<del>73</del>	<del>105</del>	

## Foreign Patent Documents

							Translation	
		Document	Date	Country	Class	Subclass	Yes	No

## OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)


Examiner

Date Considered

*20 Oct 2004*

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.